

NEW MULTI-FUNCTIONAL MICRO- AND NANOIMPRINT SOLUTION FROM EV GROUP OFFERS UNPRECEDENTED FLEXIBILITY FOR HIGH-VOLUME OPTICAL DEVICE MANUFACTURING – January 19, 2022

EV Group (EVG), a leading supplier of wafer bonding and lithography equipment for the MEMS, nanotechnology and semiconductor markets, today introduced the EVG®7300 automated SmartNIL® nanoimprint and wafer-level optics system. The EVG7300 is the company's most advanced solution to combine multiple UV-based process capabilities, such as nanoimprint lithography (NIL), lens molding and lens stacking (UV bonding), in a single platform. This industry-ready, multi-functional system is designed to serve advanced R&D and production needs for a wide range of emerging applications involving micro-and nano-patterning as well as functional layer stacking.

